

Design, Fabrication and Characterization of Capacitive Humidity Sensors based on Emerging Flexible Technologies

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Abstract: This work presents a case-based comparison between two emerging fabrication techniques for the development of conductive patterns for flexible electronics: inkjet-printing and nanographene production by laser-scribing. In particular, these two methods are used to fabricate planar interdigitated electrode (IDE) capacitors with Kapton[®] HN polyimide as supporting flexible substrate. Silver-based electrodes are manufactured by inkjet-printing, while a laser-scribing technique is used to obtain laser-reduced graphene oxide (laser-rGO) patterns from deposited graphene oxide (GO) and laser-induced graphene (LIG) layouts from the bare polyimide substrate. The comparison is focused on the application of these IDE capacitors as relative humidity (RH) sensors. The different sensors are benchmarked in terms of sensitivities to RH as well as thermal drift and linearity considering frequency dependencies. The results show that the manufactured capacitors exhibit a very competitive performance as capacitive structures when compared with other similar capacitive sensors from the literature. Furthermore, inkjet-printed and LIG-based capacitors stand out for its thermal stability and linearity.

Keywords: capacitive sensor; inkjet-printing; laser-induced graphene; laser-reduced graphene oxide; nanographene laser-scribing; relative humidity

1. Introduction

Flexible thin-film electronics is called to be one of the main actor in the more-than-moore domain, targeting auspicious applications for several areas in science and technology [1]. The rising interest in this field lies on its inherent advantages such as lightweight, flexibility and long-lasting durability, combined with cost-effective manufacturing processes [2]. Two basic approaches can be considered for the development of flexible electronics: One of them is the transfer-and-bond procedure, which consists of transferring complete circuits to flexible substrates. This technique, although intended for the development of flexible high-performance devices, requires of sophisticated fabrication processes and suffers from low scalability [3]. The other alternative is the direct production of the circuit on the flexible substrate, which bears the manufacturing of large-area electronics and yields to simpler technological processes. This approach, in turn, includes different manufacturing technologies, such as conductive inkjet-printing and nanographene laser-scribing [4-7], which are the alternatives followed in the present work.

These technologies have the advantage of being compatible with roll-to-roll techniques, enabling an inexpensive mass-production of samples. Besides, as an asset over other printing techniques, the inkjet-printing and laser-scribing processes do not precise of the use of lithographic masks or screens

46 to define the desired layout on the substrate surface; being both *contact-less*: the process is carried out
47 without physical contact between the nozzle (inkjet-printing) or the laser head (laser-scribing) and
48 the substrate. Another point in favor of these technologies is the high resolution and small thickness
49 that can be achieved when compared with other techniques such as screen printing [8]. Previous
50 studies have already opted for these procedures to fabricate capacitive structures. Examples of them
51 are found in the literature [9, 10], where the direct laser writing technique is used to develop
52 graphene-based flexible supercapacitors, or the work presented by Chen et al. [11], where
53 supercapacitors on cloth fabrics and flexible substrates are manufactured by inkjet-printing.

54 The present work addresses the design, fabrication and characterization of different capacitive
55 relative humidity (RH) sensors based on interdigitated electrodes (IDEs) and manufactured by both
56 of these methods on a commercial polyimide thin-film substrate. The same capacitive IDE structure
57 has been defined with the different proposed techniques: One made by inkjet printing of silver
58 nanoparticles, another one by laser-reduction of graphene oxide (laser-rGO) and the third one by
59 laser-induction of porous graphene (LIG) directly on the substrate [12-14]. We have characterized
60 these capacitive structures as RH sensors using a climate chamber for different environmental
61 conditions (ranging the temperature at a fixed value of humidity and vice versa) as well as working
62 frequencies to evaluate and compare their performance. This work is structured as follows: after this
63 introduction, Section 2 summarizes the different materials used in our experiments as well as the
64 methodologies followed for the fabrication and characterization of the samples. Section 3 presents
65 the results of both structural and electrical characterization of the inkjet-printed and laser-scribed
66 layers, together with a discussion of the capacitive sensors in terms of sensitivity to humidity,
67 linearity, losses and thermal drift. Finally, the main conclusions are drawn in Section 4.

68 2. Materials and methods

69 2.1. Materials

70 Kapton® HN films with a thickness of 125 μm were used as a flexible substrate for the
71 implementation of the designed capacitors.

72 The inkjet-printed patterns were made of DGP 40LT-15C silver ink (from ANP USA Inc.) with
73 an average content of 30% silver nanoparticles (NPs) dissolved in triethylene glycol monoethyl ether
74 (TGME).

75 The graphene-oxide was obtained by in-house oxidation and sonic exfoliation of graphite
76 powder (from Sigma-Aldrich) following a modified version of Hummers and Offerman method [15].
77 First, the graphite was oxidized in an ice bath with sulfuric acid (H_2SO_4), sodium nitrate (NaNO_3) and
78 potassium permanganate (KMnO_4). Then, the resulting aqueous solution was filtered with
79 hydrochloric acid (HCl) and washed (H_2O) to remove the remaining ions. Finally, the dispersion was
80 sonicated in a concentration of 4 mg mL^{-1} for 30 min, which causes its layer splitting [16].

81 2.2. Fabrication processes

82 The inkjet-printed patterns were defined with a DMP-2831™ Dimatix printer (from Fujifilm
83 Dimatix Inc.), which has already been used for this kind of applications [17]. The printing of the Ag
84 ink layout over the Kapton® polyimide surface was performed under the following conditions: Drop-
85 to-drop distance of 50 μm (being the landing diameter of 100 μm), temperature of 60 °C while printing
86 followed, after drying, by a photonic sintering step (Sinteron 2010 from Xenon) with 5 pulses of an
87 energy of 2.5 kV and a time lapse of 500 μs . Only one layer was needed to define the IDE structure.

88 The laser-scribing was performed using an in-house developed Computerized Numeric Control
89 (CNC) driven laser diode, bypassing the use of lithographic masks. The laser head is able to modulate
90 its power in the range from 15 to 300 mW at a fixed wavelength of 405 nm; while the engraving spatial
91 resolution of 20 μm is given by the motors' mechanical step. Two different experimental approaches
92 were considered for the preparation of the samples using this setup. First, the laser was used for the
93 photothermal reduction of a graphene oxide (GO) film, prepared by drop coating on the Kapton® HN
94 polyimide surface and dried in a vortex shaker (about 24h). Secondly, for the direct laser

95 photothermal ablation of the Kapton® HN polyimide, which induces in its surface graphene-derived
96 patterns with high electrical conductivity [18].

97 2.3. Capacitive sensors design

98 The previous fabrication processes were employed to develop planar IDE capacitive RH sensors
99 [19-21]. The intrinsic properties of polyimides, such as its effectiveness to absorb moisture and its
100 stability at a wide range of temperatures, make this substrate a perfect choice for the manufacturing
101 of inexpensive RH sensors. These sensors, schematized in Figure 1.a and photographed in Figure 1.b,
102 were designed following the IDE layout dimensions summarized in Table 1. Capacitive-type
103 transducers offer several advantages over the resistive-type ones, such as linear humidity-
104 capacitance relationship for a given frequency, which makes easier the definition of a calibration
105 curve, and a wider RH range of operation [22]. The capacitance of these structures is intimately
106 related with the relative dielectric constant (ϵ_r) of the insulators which, in the case of the Kapton®
107 HN polyimide, increases with respect to the relative humidity (RH(%)) and decreases as the
108 frequency (f) increases [23]:

$$\epsilon_r = F(\epsilon_{o,r}, \text{RH}(\%), f) \quad (1)$$

109 being $\epsilon_{o,r}$, dependent on the polyimide substrate. Moreover, although planar capacitors might have
110 lower performance than parallel plate ones, the interest in planar IDE structures lies on its
111 compactness and low thickness, which is particularly useful when the sensor is used as a conformal
112 patch [24].

113 In this study, the performance of these RH sensors is evaluated as a function of the technology
114 of the electrodes and the material between them, since they share the same flexible substrate and
115 layout but different resolutions and thicknesses.

116 2.4. Electrodes characterization

117 The structural and electrical characterization of the electrodes of the capacitors are key aspects
118 for the assessment of their performance, especially, for the laser-rGO and LIG ones. As reported by
119 previous works, the electrical conductivity of the laser-derived graphene aggregates presents a strong
120 dependence with the level of photothermal ablation of the raw material, which in turn depends on
121 the power used during the scribing process [18, 25]. Therefore, the analytical structure and
122 conductivity of the electrodes were studied as a function of the laser power with the purpose of
123 optimizing the laser photoablation process. First, both rGO and LIG patterns were electrically
124 characterized using the Transmission Line Model (TLM) method [26]. Once the sheet resistance of
125 the samples was optimized as a function of the laser power, the resulting layer constituting the
126 electrodes was structurally characterized by Scanning Electron Microscopy (SEM), Infrared (IR)
127 spectroscopy, Raman spectroscopy, and X-ray Photoelectron Spectroscopy (XPS).

128 SEM images were acquired at an extraction and acceleration voltage of 5 kV using the field-
129 emission scanning electron microscope NVision40 from Carl Zeiss. The Kratos X-ray photoelectron
130 spectrometer model Axis Ultra-DLD were used for the XPS experiments. The samples were
131 characterized in a vacuum chamber at a pressure 10^{-10} Torr using an X-ray power of 450 W. The
132 Raman spectra acquisition was carried out in a JASCO NRS-5100 dispersive micro-Raman
133 spectrometer with an excitation source of $\lambda = 532$ nm (Elforlight G4-30; Nd:YAG). Finally, two
134 different techniques were used for the IR spectroscopy, the rGO-based electrodes spectra were
135 obtained using attenuated total reflectance Fourier transform infrared (ATR-FTIR) spectroscopy,
136 while Diffuse Reflectance Infrared Fourier Transform (DRIFT) was used for the LIG-based electrodes
137 since the ATR-FTIR is not sensitive enough in this case [27]. Both techniques were carried out using
138 a Bruker Tensor 27 spectrometer.

139 2.5. Capacitive sensors characterization

140 The capacitance and parasitic resistance of the fabricated capacitors was measured as a function
141 of the relative humidity and temperature using the four-wires measurement technique with the

142 impedance analyzer 4294A and the impedance probe kit 42941A (from Keysight). The connection
143 between the analyzer and the electrodes was done through a mini-SMA (SubMiniature version A)
144 connector glued to each electrode using silver-filled epoxy EPO-TEK®H20E (from EpoxyTechnology,
145 Inc.). The measurements were performed using a sinusoidal excitation signal of 0.5 V of amplitude.
146 Furthermore, the samples were also characterized as a function of the frequency, ranging from 1 kHz
147 to 10 MHz.

148 The climate chamber VCL 4006 (from VötschIndustrietechnik GmbH) was used for the
149 characterization of the capacitive sensors under different environmental (humidity and temperature)
150 conditions. In our experiments, the humidity was ranged between 30% and 90%, while the interval
151 of temperature was varied from 15 °C to 65 °C.

152 The whole characterization setup was automatized using the Labview 2016 software (from
153 National Instruments Corporation).

154 3. Results and discussion

155 3.1. Electrodes characterization

156 The equivalent circuit of capacitors are the critical factors influencing their performance. An IDE
157 planar capacitor can be modelled as an $R_s + R_p || C$ association, being R_s the equivalent series
158 resistance, R_p the equivalent parallel resistance and C its capacitance. Then, aiming to maximize the
159 power density and to minimize the self-discharge of the capacitive structure, R_s should be reduced to
160 the minimum possible while R_p should be as large as possible [28]. In our case, the series resistance is
161 related to the sheet resistance of the electrodes, and therefore, the manufacturing processes must be
162 optimized to minimize the resistivity of the conductive patterns.

163 In the case of the Ag-loaded electrodes, the sheet resistance is strongly related to the sintering
164 method; while the conductivity of the nanographene-based ones depends on the laser photothermal
165 power. In our experiments, we selected the photonic sintering since, as reported by a previous work
166 [29], it can decrease the sheet resistance of the Ag ink down to 55 mΩ sq⁻¹ within a few milliseconds,
167 whereas the sheet resistance of the graphene-derived patterns was studied as a function of the laser
168 ablation level. For that purpose, the laser power was ranged from 65 mW to 100 mW at an excursion
169 rate of 3 min cm⁻² to ensure surpassing the ablation threshold-power [30]. As observed in Figure 2,
170 the sheet resistance of both LIG and rGO patterns presents a strong dependence with the laser power.
171 On one hand, when the laser power is increased the sheet resistance of the rGO decreases
172 exponentially from over-MΩ to sub-kΩ. On the other hand, the LIG presents a softer decay. In both
173 cases, the sheet resistance is reduced down to the value of ~250 Ω sq⁻¹. According to these results, a
174 laser power of 100 mW was selected to minimize the resistance of both type of electrodes.

175 SEM images of Figure 3 show the morphology of both nanographene-derived patterns and Ag-
176 ink layer. As seen in Figure 3a, the rGO shows a plate-shape structure with multiple cracks as a result
177 of the photothermal reduction of the GO which indicates that the laser is able to restore, at least
178 partially, the crystallographic structure of carbon bonds which was disrupted during the oxidation
179 process [31]. In the case of the ablated Kapton® (Figure 3b), the irradiated regions show a foam-like
180 morphology which is a defining feature of the LIG [13]. Besides, it can be appreciated that for the
181 rGO sheets the reduction process supposes a thickness decrease of the original thickness of the GO
182 film and an increase of the thickness for the LIG patterns over the Kapton® film, which is consistent
183 with what was reported in previous works [13, 32]. It can be also seen that the engraving resolution
184 limits the effective area of the conductive layers in both laser-treated materials. This makes the sheet
185 resistance higher than that obtained for the Ag-ink layer since this latter, as observed in Figure 3c, is
186 more uniform although also presents some surface porosity.

187 Raman spectroscopy and X-ray photoelectron spectroscopy confirm the graphene-derived
188 nature of the rGO and LIG electrodes. On one hand, as observed in Figure 4a, the Raman spectra are
189 dominated by three peaks: the D-peak (~1350 cm⁻¹), the G-peak (~1580 cm⁻¹) and the 2D-peak (~2700
190 cm⁻¹). These peaks are often present in disordered graphene-based materials and its ratio gives a
191 quantification of the disorders and defects of its structure [33]. The G-peak is characteristic in sp²-

192 hybridized carbon networks, meanwhile the D-peak comes from the structural imperfections [34].
193 Therefore, an estimation for the degree of disorder can be obtained from the ratio I_D/I_G . In this case,
194 this ratio ($I_D/I_G \approx 1$) points out a larger disorder in the structure of the LIG than in its rGO counterpart.
195 The 2D-peak gives information about the number of layers of the graphite structure; its intensity
196 increases as the number of layers decreases. Besides, there is no appreciable shift in D and 2D peaks
197 position in both materials, while the G peak of the LIG presents a slight deviation, which might be
198 associated to its larger number of defects [33]. In this way, according to the Raman spectroscopy
199 results, we can infer that the LIG structure presents a lower crystallographic quality with respect to
200 the rGO one.

201 On the other hand, the XPS spectrum helps to identify the remaining non-desirable bonds after
202 the processing of the raw materials. Figure 4b shows the high resolution C1s peak of the XPS spectra
203 for both LIG and laser-rGO electrodes. The Gaussian decomposition was resolved using the CasaXPS
204 software (from Casa Software Ltd). As can be seen, the laser irradiation is able to break most of the
205 C-N, C-O-C and C=O bonds which compose the Kapton® HN polyimide film and the C-OH, C=O
206 and O=C-O bonds of the GO structure [35-37]. The resulting graphene-based materials are basically
207 composed by carbon configurations, with prevalence of the sp^2 carbon aromatic rings (C-C), which is
208 in agreement with the Raman spectroscopy results. In the case of Ag NPs patterns, XPS experiments
209 of Figure 4c reveals the dominance of metallic silver, as confirmed by the $3d_{5/2}$ and $3d_{3/2}$ components
210 (located at 368.1 eV and 374.1 eV, respectively) [38, 39]. These results also present a small content of
211 carbon which remains from the TGME solvent after the drying and sintering steps, as observed in
212 inset of Figure 4c.

213 IR spectroscopy also supports these results, Figure 5a shows how the reduction process of the
214 GO significantly reduces the stretching vibrations of the hydroxyl groups (-OH) and water molecules
215 presented in the range $3700-2800\text{ cm}^{-1}$ as well as at $\sim 1614\text{ cm}^{-1}$ and 1347 cm^{-1} . Besides, the broad peak
216 in the range $966-1090\text{ cm}^{-1}$ presented in the GO due to the epoxy groups (C-O-C) is also significantly
217 reduced, while the peak at 1580 cm^{-1} indicates that the C=C band was restored [40-42]. As seen, the
218 laser is able to remove various oxygen containing functional groups, although some carbonyl and
219 epoxy groups (C-O-C) still remain after the reduction process. In the case of the Kapton® polyimide
220 (Figure 5b), the aromatic C-H stretching modes, the imide C-N groups as well as the phenyl ether
221 linkages (C-O-C) which compose its chemical structure present a significant reduction, whereas the
222 change in the intensity of peaks at 1500 cm^{-1} and 1600 cm^{-1} reveals an increase in the aromaticity of
223 the irradiated surface [43].

224 The resolution of the printing and scribing processes is also an important aspect for the
225 performance of the capacitors [20, 21]. Therefore, we analyzed the real physical dimensions of the
226 printed and laser-scribed electrodes under the microscope (see Figure 1b) to establish a comparison
227 between the designed layout (Table 1) and the experimental one. Table 2 presents the resolution
228 achieved by both methods, where uncertainties were calculated as the standard deviation of the
229 experimental data. As seen, inkjet patterns have better precision (for the experimental setup
230 considered), especially for the smallest features. Moreover, as can be seen in Figure 1b, the inkjet-
231 printed electrodes are more uniform than the obtained by laser-scribing, which present an
232 appreciable outline pattern because of the laser-CNC mechanical steps.

233 3.2. Capacitive sensors characterization

234 Once the electrodes have been structurally and electrically characterized, hereinafter a
235 characterization of the sensors capacitance as a function of the RH(%) and working frequency is
236 presented. The capacitance and equivalent parallel resistance of the capacitors depicted in Figure 1
237 was measured for different values of RH(%) as a function of the frequency and at a constant
238 temperature of $40\text{ }^\circ\text{C}$ to be able to cover a broad range of RH. As expected, in all cases the capacitance
239 decreases as the frequency increases. For the LIG electrodes (Figure 6a), the capacitance decays half
240 its value, from about 8.5 pF at 1 kHz down to 4 pF at 10 MHz, whereas the response of the Ag-based
241 electrodes (Figure 6c) shows a lower dependency on the working frequency with a mean value of 5
242 pF in the whole range of frequencies analyzed. These values are consequent with the different

243 theoretical models of a coplanar IDE capacitor, such as the proposed by Qin *et al.* [44]. Moreover, for
 244 the rGO-based capacitors (Figure 6b), the capacitance at 1 kHz is about 40 pF with an exponential
 245 decay in frequency down to 5 pF at 10 MHz. As seen, the rGO capacitors present a much higher
 246 capacitance at low frequencies due to the high dielectric constant of the GO which remains between
 247 the coplanar IDE structure (as can be observed in Figure 1b). However, the capacitance reaches a
 248 similar value to the previous ones at high frequencies since the dielectric constant of the GO decreases
 249 abruptly when the frequency is increased [45].

250 The calibration curves of each sensor for an excitation source with a frequency of 1 kHz, 10 kHz
 251 and 100 kHz are represented in Figure 7. The study was also carried out for different frequencies due
 252 to the interest in fast readout sensors [46, 47]. The sensitivity of the sensor, S , which can be obtained
 253 from Eq. 2, gives information about its behavior to humidity changes [48]. Paired in importance, the
 254 linearity of the response is defined as the maximum deviation from its linear approximation (Eq. 3)
 255 [49]. Also, the hysteresis is calculated from Eq. 4, as the maximum difference of capacitance while
 256 performing the characterization by increasing and decreasing RH cyclically.

$$S = \left| \frac{\Delta C}{\Delta RH_i(\%)} \right|_{T=cte} \quad (2)$$

$$Nonlinearity = \frac{\max(C_i - C_{lf})}{C_{max}} \quad (3)$$

$$Hysteresis = \frac{\max(C_{i,increasing} - C_{i,decreasing})}{C_i} \quad (4)$$

257 being C_i the experimental capacitance measured at $RH_i(\%)$, C_{lf} its linear approximation and C_{max} the
 258 maximum capacitance. $C_{i,increasing}$ and $C_{i,decreasing}$ are the measured capacitance at $RH_i(\%)$ while increasing
 259 and decreasing steps of RH, respectively.

260 The thermal drift is obtained as the sensitivity of the developed sensor to temperature changes,
 261 considering the range from 15 °C to 65 °C (ΔT) at a constant relative humidity of 50%RH, see Eq. 5.

$$Thermal\ drift = \left| \frac{\Delta C}{\Delta T} \right|_{RH=cte} \quad (5)$$

262 A benchmarking of the parameters described above, corresponding to our transducers, is
 263 summarized in Table 3. These results are the average of several measurements carried out on different
 264 days presenting negligible changes from day to day. As can be observed, the LIG-based capacitors
 265 present higher linearity and thermal stability at the expense of a lower sensitivity. This sensitivity,
 266 which ranges from 2.0 fF/%RH to 7.44 fF/%RH as a function of the frequency, is comparable to the
 267 obtained in previous works. For example, Molina-Lopez *et al.* reported a sensitivity of 2.3 fF/%RH
 268 with an IDE structure using cellulose acetate butyrate (CAB) as sensing layer and Ag/Ni as electrode
 269 material [20], a similar structure with poly(ether urethane) (PEUT) as sensing layer and a sensitivity
 270 of 2.03 fF/%RH at 100 kHz was proposed by Altenberend *et al.* [50]. In the same way, comparable
 271 sensitivities can be found in the literature for sensors based on more complex technologies [51-53].
 272 Besides, as it has been already demonstrated in other works, the sensitivity of these capacitive sensors
 273 might be improved using different geometrical layouts [54].

274 Moreover, the inkjet-printed ones present a sensitivity up to 5 times higher than LIG-based
 275 capacitors at low frequencies, however, the sensitivity decays with the frequency while their linearity
 276 and thermal drift increase. In the case of the rGO-based electrodes, the GO layer between them makes
 277 these sensors the most sensitive, although the calibration curve fits better to a second order function.
 278 These capacitors also suffer from a low thermal stability since, as it is well known, the GO is also an
 279 outstanding thermal conductor [55]. In any case, the modelling of these calibration curves results
 280 easier than the ones from the resistive-type IDE structures, that follow logarithmic or exponential
 281 functions [56, 57].

282 Furthermore, the equivalent parallel resistance of each capacitor is plotted as a function of the
 283 frequency in Figure 8. The change in the parallel resistance with respect to the frequency is due to the

284 leakage current between the electrodes as a result of the dielectric losses when the frequency increases
285 [57]. Because of it, the self-discharge resistance decreases with respect to the frequency in all cases.
286 The best performance in terms of resistivity for the whole range of frequency is achieved by the inkjet-
287 printed capacitors followed by the LIG ones, whose higher leakage current could be directly related
288 to the less uniformity of its electrodes. The laser-rGO-based capacitors are the worst structures in this
289 context since the remaining GO layer between the electrodes facilitates the flow of the leakage
290 current. In any case, these results are very competitive when we compare them with the obtained for
291 other very similar capacitive structures from the literature, such as the presented by Li *et al.* [58],
292 where R_p ranges from $\sim 10\text{ M}\Omega$ (at 1 kHz) to $\sim 0.1\text{ M}\Omega$ (at 100 kHz). These differences in the parallel
293 resistance are also related to the different capacitance values illustrated in Figure 6. It can be noted
294 that the higher the losses are (lower R_p), the higher the measured capacitance is.
295

296 Regarding to the fabrication technologies, inkjet-printing provides the lower value of
297 capacitance, but better performance as capacitive structure (higher R_p , less losses). Besides, this
298 performance is even better for smaller sizes, as it has been already demonstrated [21, 54]. However,
299 this process is more expensive, non-environmentally friendly and slower than the LIG one since it
300 requires of a sintering step. Moreover, the LIG is the simplest method since it can be carried out
301 directly over the substrate without requiring other material or any extra fabrication steps (no
302 previous depositions or sintering processes needed). Thus, this technology allows to obtain humidity
303 sensors with a sensitivity comparable to the reported in the literature combining a high linearity with
304 a low thermal drift. Besides, the performance of these sensors would be enhanced using a higher
305 resolution engraving, which would make the LIG layer more uniform, reducing the leakage current
306 (losses), increasing the effective area and, therefore, their sensitivity. Finally, the laser-rGO based
307 capacitors provide much higher capacitance values from the same layout and more sensitivity.
308 Nevertheless, these ones also present the highest losses (lowest R_p values), non-linearity and thermal
309 drift so a rGO-based solution does not result the best choice as capacitive humidity sensors. In fact,
310 this technology is usually better suited for the development of resistive thermistors [25, 59].
311

312 Summarizing, the main difference between the graphene-based capacitors and the Ag-ink ones
313 lies on the sheet resistance and uniformity of the conductive layer. Besides, the rGO-based sensor
314 presents the singularity of having a remaining layer of unreduced GO in-between its electrodes. On
315 one hand, this latter feature makes the rGO-based capacitors much more sensitive than both LIG and
316 Ag-ink ones, since the GO dielectric constant is very sensitive to humidity and temperature changes
317 (in contrast to air). Therefore, this also makes the rGO-based sensor thermally less stable and
318 facilitates the current leakage between electrodes. On the other hand, the LIG electrode is less uniform
319 and less conductive than the Ag-ink one, which increase the losses and make these sensors less
320 sensitive.
321

322 Finally, as an example of how fast the developed sensors are, the dynamic response of the Ag-
323 based capacitor is depicted in Figure 9. It can be note that our flexible humidity sensor presents a
324 higher response time (~ 3.5 times slower) than the widely-used rigid sensor SHT31 (from Sensirion
325 AG). Besides, this time is intimately related to the sheet resistance of the conductive patterns, being
326 greater as the sheet resistance increases [60], and to the thickness of the sensitive layer [61].

327 5. Conclusions

328 Flexible planar IDE capacitive humidity sensors have been compared as a function of the
329 materials and techniques used for its fabrication. Inkjet-printing and laser-scribing techniques have
330 been used to fabricate three different capacitors (Ag-ink, laser-rGO and LIG) over a Kapton®
331 polyimide substrate with the same IDE layout. The structures have been characterized in terms of
332 RH sensitivity, linearity, thermal drift, losses and frequency response. The results obtained have
333 demonstrated that the LIG-based capacitors present a higher linearity response to humidity changes
334 (0.5% of non-linearity at 10 kHz) and the best thermal stability (3.26 fF/°C at 10 kHz) with a sensitivity

335 (ranging from 2 fF/%RH to 7.44 fF/%RH) very competitive when compared with other similar sensor
336 from the literature. On the contrary, the laser-rGO and inkjet-printing based capacitors are much
337 more sensitive to humidity changes (up to 100 and 5 times higher, respectively), keeping a
338 competitive value of sensitivity when the frequency is increased but presenting a higher thermal drift.
339 The inkjet-printed capacitors also stand out for their low losses and the possibility of operating at
340 higher frequencies, while the thermal drift and a higher non-linearity coefficient of the rGO capacitors
341 are their main disadvantages in comparison to the other two structures studied.

342 **Acknowledgments**

343 This research was funded by the Spanish Ministry of Education, Culture and Sport (MECD), the
344 European Union and the University of Granada through the project TEC2017-89955-P, the pre-
345 doctoral grant FPU16/01451, the fellowship H2020-MSCA-IF-2017 794885-SELFSSENS and the grant
346 "Initiation to Research". The authors would like to thank the support of the JSPS KAKENHI through
347 the grant number JP18K04275 and the support of the Institute for Cognitive Systems from the
348 Technical University of Munich for the use of the inkjet printer.

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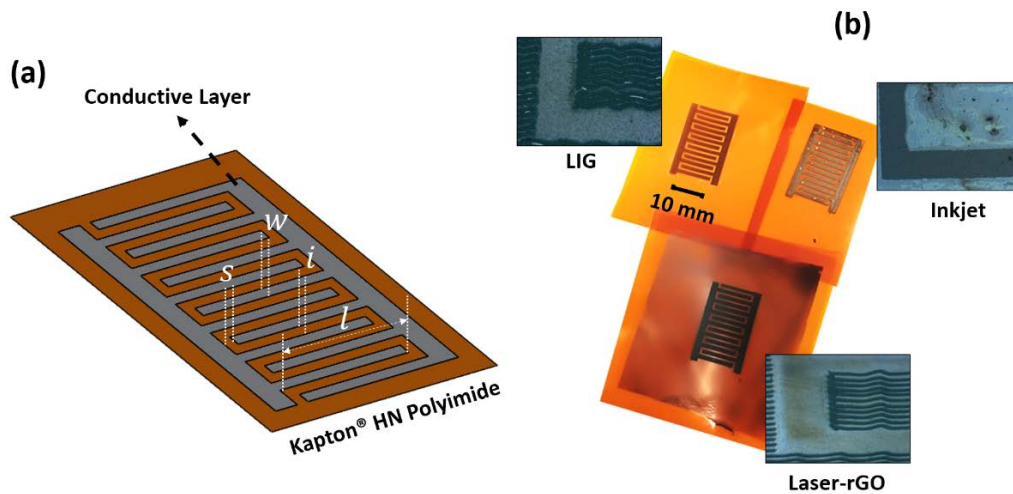
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523 **Figures and Tables**



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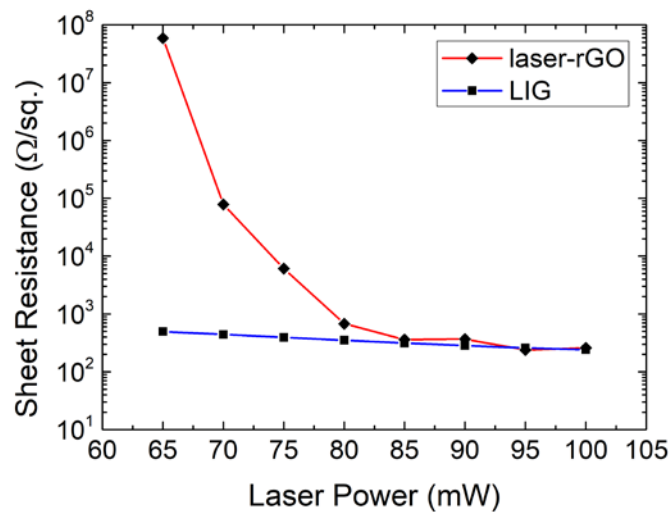
525 Figure 1. (a) Planar IDE capacitor on Kapton® HN polyimide substrate (w : finger width; s : electrode
 526 separation; i : finger interspacing; l : finger length). (b) Actual photographs and microscope images of
 527 an Ag-ink printed electrode, a laser-induced graphene electrode and a laser-rGO electrode.

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Table 1. Planar IDE capacitors layout description.

Parameter	Value
Number of fingers	13
Fingers length (l)	10 mm
Fingers width (w)	1 mm
Fingers interspacing (i)	0.5 mm
Electrodes separation (s)	0.5 mm

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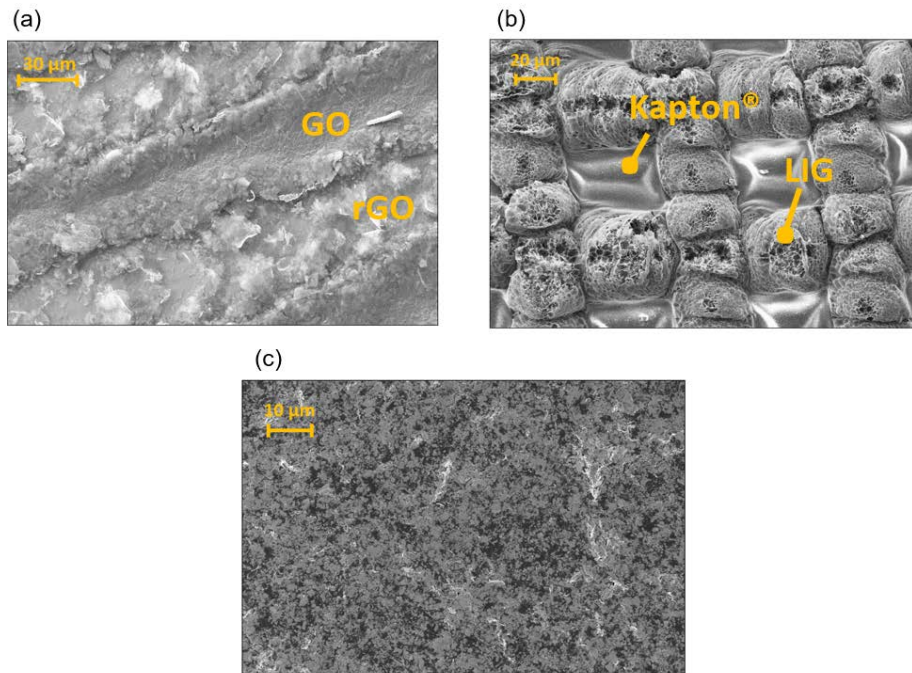


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531 **Figure 2.** Sheet resistance of the LIG and laser-rGO as a function of the laser power used for the
 532 photoablation of the polyimide surface and the graphene oxide reduction respectively. The laser
 533 excursion rate was set to 3 min cm⁻².

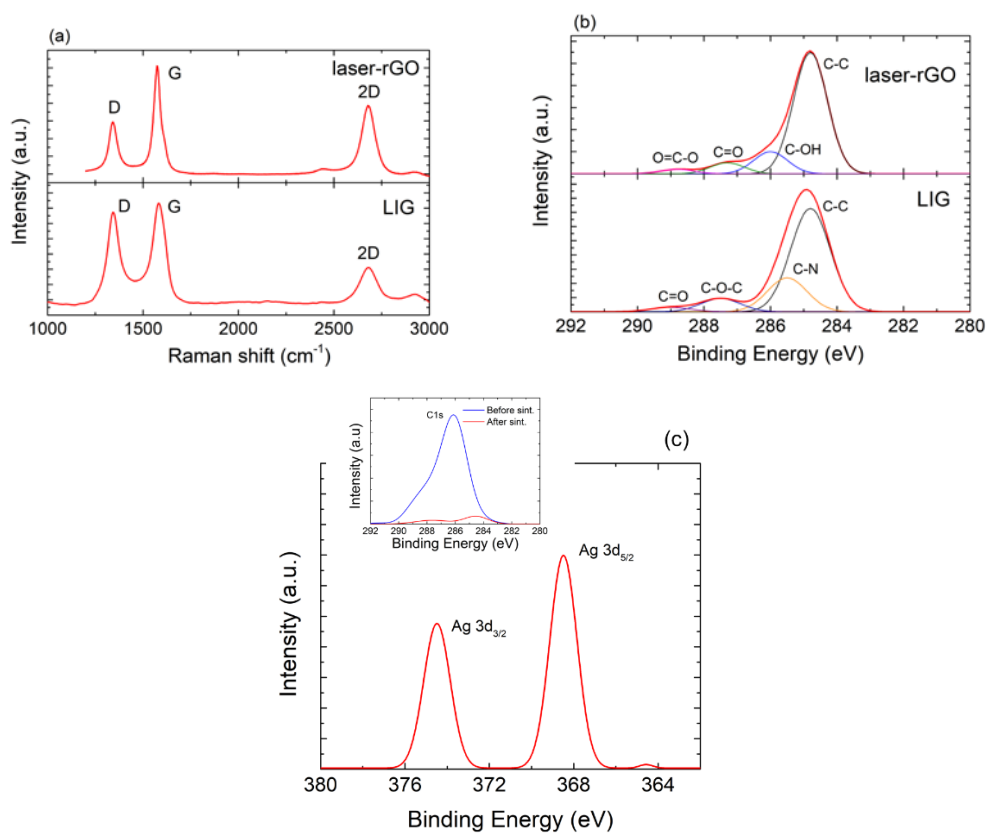
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537 **Figure 3.** (a) SEM image of a laser-reduced GO sample (scale: 30 μm, extraction and acceleration
 538 voltage: 5 kV, working distance: 6.0 mm). (b) SEM image of a laser-ablated Kapton® sample (scale: 20
 539 μm, extraction and acceleration voltage: 5 kV, working distance: 6.0 mm). (c) SEM image of an Ag-
 540 ink sample (scale: 10 μm, extraction and acceleration voltage: 5 kV, working distance 6.0 mm).



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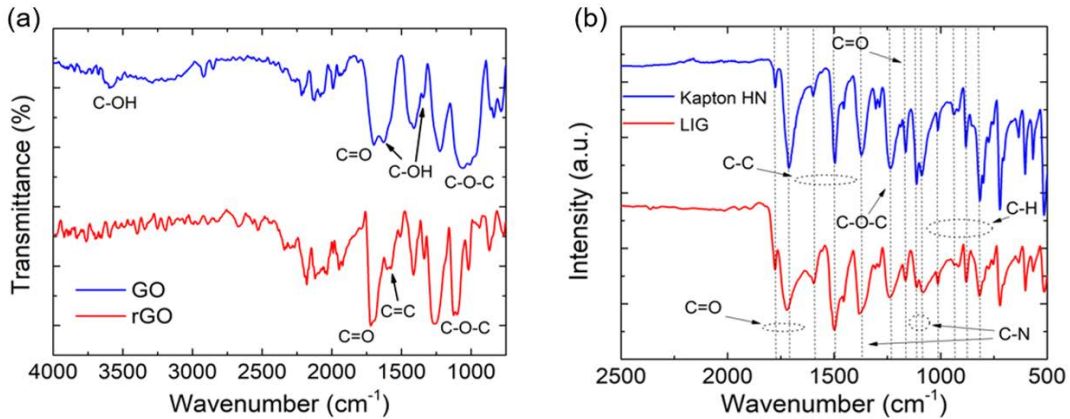
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Figure 4. (a) Comparison of the Raman spectra obtained from the laser-rGO and LIG sheets. The laser
 power used to produce the samples was 100 mW at an excursion rate of 3 min cm⁻². (b) Comparison
 of the C1s peaks from the XPS spectrum of LIG and laser-rGO. The laser excursion rate was set to 3

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min cm⁻² for a laser power of 100 mW. (c) XPS spectrum of Ag 3d core level of Ag-ink patterns after drying and sintering steps. Inset shows a comparison of the C1s peaks before and after these steps.



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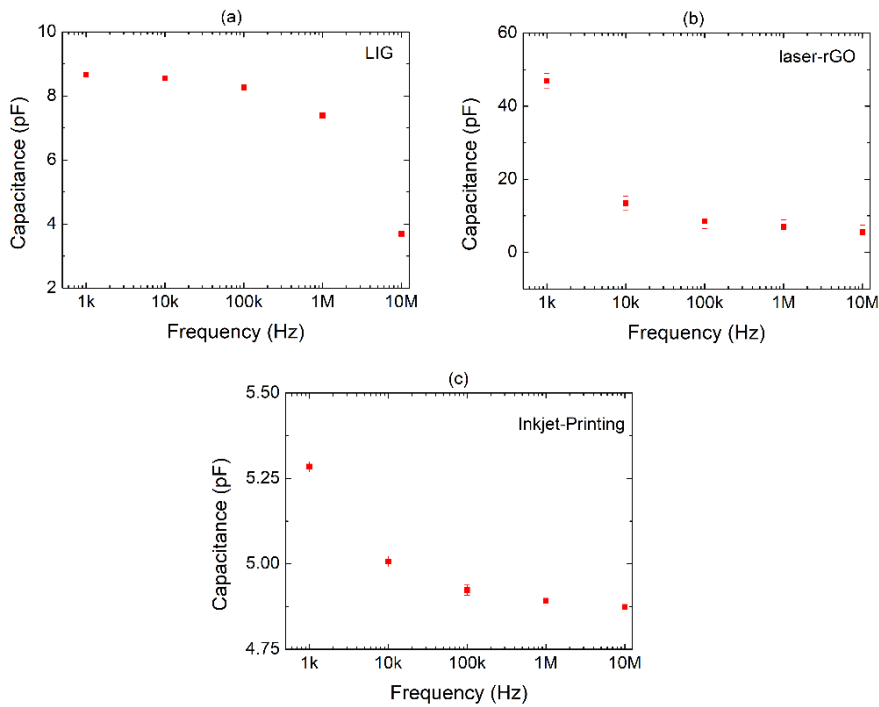
Figure 5. (a) ATR-FTIR spectroscopy of the GO before and after the reduction. (b) DRIFT spectra of the Kapton® polyimide before and after the laser irradiation. (number of scans: 1024, resolution 1 cm⁻¹).

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Table 2. Planar IDE capacitors: theoretical and experimental dimensions.

Parameter	Model (mm)	Laser-rGO & LIG (mm)	Inkjet-printed (mm)
Fingers length (<i>l</i>)	10	10.4 ± 0.5	9.8 ± 0.2
Fingers width (<i>w</i>)	1	1.32 ± 0.13	1.02 ± 0.05
Fingers interspacing (<i>i</i>)	0.5	0.55 ± 0.02	0.47 ± 0.04
Electrodes separation (<i>s</i>)	0.5	0.54 ± 0.02	0.51 ± 0.05

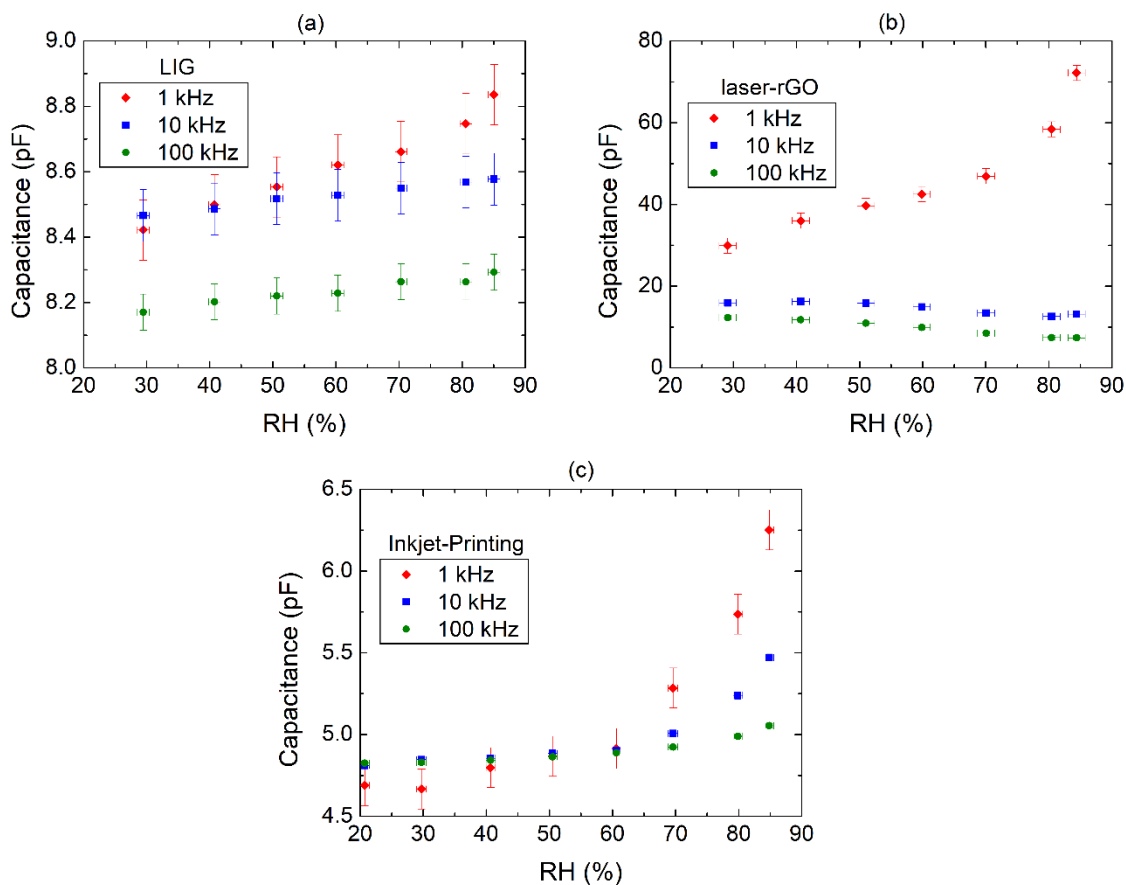
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Figure 6. Capacitance as a function of the frequency at 70%RH, and a fixed temperature of 40 °C for the capacitors with LIG-based electrodes (a), laser-rGO-based electrodes (b) and inkjet-printed ones (c). Error bars according to the hysteresis loop due to the increase/decrease of RH are shown.



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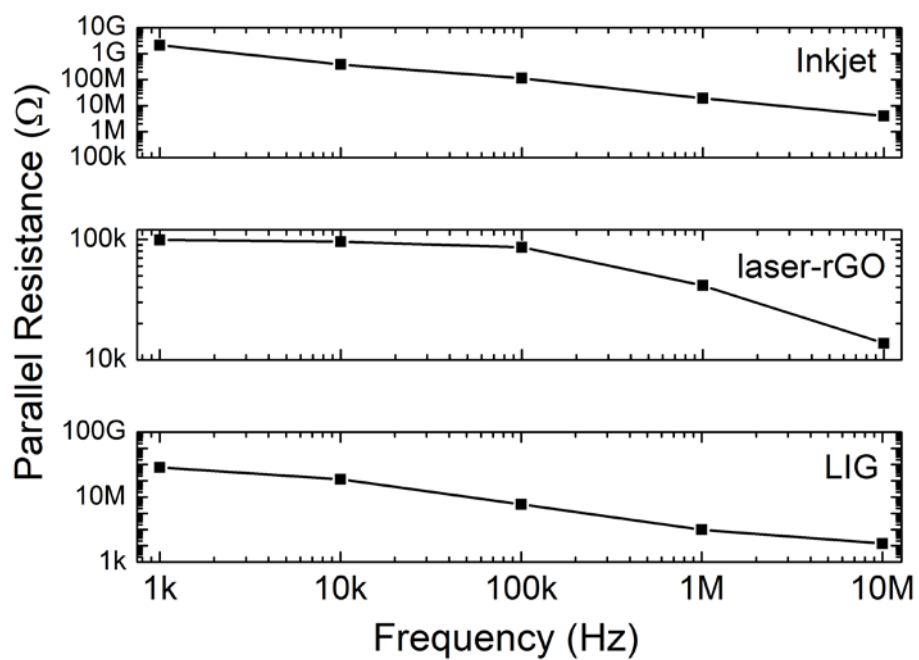
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Figure 7. Response of the humidity sensors: capacitance as a function of the relative humidity, RH(%), for three frequencies at a fixed temperature of 40 °C. Error bars according to the hysteresis loop due to the increase/decrease of RH are shown.

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Table 3. Comparison among the three different flexible capacitive humidity sensors.

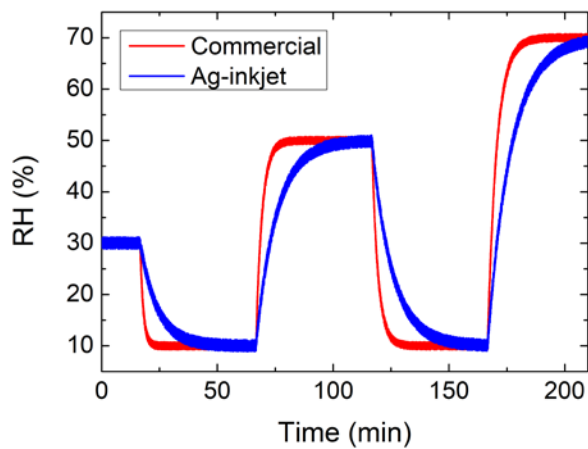
	LIG	Laser-rGO	Inkjet
Sensitivity (fF/%RH)	7.44 at 1 kHz	764 at 1 kHz	24.71 at 1 kHz
	2.00 at 10 kHz	66.28 at 10 kHz	10.28 at 10 kHz
	2.20 at 100 kHz	89.32 at 100 kHz	3.57 at 100 kHz
Nonlinearity	0.50% at 1 kHz	4.81% at 1 kHz	7.07% at 1 kHz
	0.29% at 10 kHz	4.76% at 10 kHz	1.43% at 10 kHz
	0.33 at 100 kHz	5.41% at 100 kHz	1.04% at 100 kHz
Thermal drift (fF/°C)	< 1 at 1 kHz	218.63 at 1 kHz	17.20 at 1 kHz
	5.88 at 10 kHz	60.01 at 10 kHz	23.81 at 10 kHz
	4.47 at 100 kHz	73.06 at 100 kHz	26.24 at 100 kHz
Equivalent parallel resistance (MΩ) at 50%RH	678 at 1 kHz	0.100 at 1 kHz	2100 at 1 kHz
	123 at 10 kHz	0.097 at 10 kHz	385 at 10 kHz
	3.72 at 100 kHz	0.086 at 100 kHz	110 at 100 kHz



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Figure 8. Equivalent parallel resistance, R_p , of the capacitive structures as a function of the frequency measured at the fixed conditions of 50%RH and 40 °C.



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Figure 9. Transient response of the Ag-ink IDE capacitor.